

Preparation and Characterization of Several II-IV-V₂ Chalcopyrite Single Crystals

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Single crystals of ZnSiP₂, ZnGeP₂, ZnGeP_{1.8}As_{0.2}, and ZnGeP_{1.6}As_{0.4} have been grown by several techniques and their electronic and optical properties were compared. For ZnSiP₂ there are marked absorption bands at 10 and 11.5 μm, and at 13 μm for ZnGeP₂. Upon substitution of 10 mole% of arsenic for phosphorus, the latter band does not shift to higher wavelengths. Further substitution of arsenic for phosphorus in ZnGeP₂ showed a weak second band at 9.8 μm. © 1987 Academic Press, Inc.

Introduction

The ternary compounds ZnSiP₂ and ZnGeP₂ are semiconductors which crystallize with the chalcopyrite structure (space group $I\bar{4}2d$). An excellent review discussing the formation and properties of this class of compounds was presented by Borshchevskii *et al.* (1). ZnSiP₂ has been reported to melt at 1250°C (2) and single crystals were obtained from a molten zinc or tin flux (2, 3) as well as by chemical vapor transport (3-6) using Cl₂, CCl₄, ZnCl₂, or I₂ as the transport agent. There has been no report of crystal growth from the melt.

Single crystals of ZnGeP₂ have been grown from the melt (4, 6-8) or from molten metal fluxes (3, 4, 9-11). ZnGeP₂ has also been grown by chemical vapor transport using excess phosphorus as the trans-

port agent (8). These materials show low absorption in the wavelength range from their optical band gap to the IR absorption band (13 μm for ZnGeP₂).

Despite the relatively large number of publications describing various properties of these compounds, there has been no comparative study of the crystal growth process and the electronic and optical properties of these phases. Single crystals of members of the solid solution ZnSiAs_xP_{2-x} have been grown by chemical vapor transport using iodine as the transport agent (3). However, only the variation of lattice parameters as a function of composition was reported in this study. There have been no reports concerning the substitution of arsenic for phosphorus in ZnGeP₂. The extent of arsenic substitution into ZnGeP₂, as well as the effect on both the observed optical and electronic properties, is included in this study of these chalcopyrites.

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Experimental

ZnSiP₂ Single Crystals

Growth from a zinc flux. Single crystals of ZnSiP₂ were grown from a zinc flux. The zinc metal (Gallard and Schlesinger, 99.9995) was prereduced in a Ar/H₂ (85/15) atmosphere at 200°C for 3 hr. Silicon and phosphorus (Gallard and Schlesinger, 99.999) were used without further purification. The molar ratio of the reactants was 60:1:2 (Zn:Si:P). Approximately 20 g was placed in a silica tube which was then evacuated to 3 μm Hg, sealed, and heated in a furnace at 20°C/hr to 1000°C. After a soaking period of 24 hr at this temperature, the furnace was cooled at a constant rate of 5°C/hr to 500°C. The tube was then allowed to cool to room temperature and opened. Crystals were retrieved by leaching away the solidified flux with hot dilute (2 M) hydrochloric acid. The crystals were red and the maximum size was 8 × 2 × 1 mm³.

Growth by chemical vapor transport. Single crystals of ZnSiP₂ were also synthesized by chemical vapor transport using chlorine as the transport agent. Charge compositions in the molar ratio 1:1:2 were introduced into silica tubes which were then evacuated to 2 μm Hg and 100 Torr of Cl₂ was then added to the transport tube which was then sealed. The transport tube was placed in a three-zone furnace and the charge prereacted at 700°C for 24 hr with the growth zone maintained at 970°C, in order to prevent transport. The furnace was equilibrated to give a constant temperature zone across the reaction tube and was then programmed to give, in 24 hr, the temperature gradient necessary for single crystal growth to take place. Crystals grew in the cooler zone of the furnace with experiments generally running 20 days. A gradient of 1000–970°C was used and polyhedral crystals 5 × 3 × 3 mm³ were obtained.

ZnGeP₂ Single Crystals

Growth by chemical vapor transport. Single crystals of ZnGeP₂ were also grown by chemical vapor transport using chlorine as the transport agent. The germanium used was obtained from Cominco (7-9's, resistivity 50 Ω-cm). The growth procedure was similar to that described for ZnSiP₂. However, a temperature gradient of 980–950°C was used. Polyhedral crystals 8 × 5 × 3 mm³ were obtained.

Growth from the melt. ZnGeP₂ boules were grown by a modified Bridgman method. The charge which contained 2 g of reactants and 2% excess phosphorus was placed in a graphite Bridgman-shaped crucible and then sealed in a silica tube; the charge was then prereacted in an argon-pressurized furnace. The argon back pressure was maintained at 26 atmospheres and the heating was carried out in three stages. Initially, the temperature was 600°C for 24 hr, then 800°C for 24 hr, and finally 900°C for 24 hr. The tube was transferred to a vertical furnace equipped with a puller/rotor action motor. The motor was used to ensure uniform heating across the growth ampoule during crystal formation. The charge was allowed to reach a temperature of 1070°C. The growth ampoule was maintained at this temperature for 48 hr. The maximum temperature was then lowered to 1040°C and the ampoule was allowed to pass through a temperature gradient of 3°C/cm at the liquid–solid interface at a rate of 0.2 mm/hr for a period of 1 week. The size of the boule was 2.5 cm × 0.7 cm. A 1-mm slice was removed and discarded from both the top and bottom of each boule.

Arsenic-Substituted ZnGeP₂ Single Crystals

Arsenic was introduced into the chemical vapor transport tubes and the conditions for crystal growth were maintained the same as for pure ZnGeP₂. In addition,

boules of $\text{ZnGeP}_{1.8}\text{As}_{0.2}$ and $\text{ZnGeP}_{1.6}\text{As}_{0.4}$ were obtained from the melt by a procedure similar to that used for the growth of pure ZnGeP_2 . However, these boules must be annealed at 700°C for at least 2 days to ensure uniform distribution of the arsenic. Powder diffraction patterns of ground single crystals were obtained with a Norelco diffractometer using monochromatic radiation from a high-intensity copper source ($\lambda\text{-CuK}\alpha_1 = 1.5405 \text{ \AA}$). Cell parameters were determined from slow-scan ($\frac{1}{4}^\circ/\text{min}$) diffraction patterns over the range $12^\circ < 2\theta < 72^\circ$. The reflections were indexed on unit cells determined from studies of previous investigations (12, 13) and the precise lattice parameters were obtained using a least-squares refinement from these reflections.

Optical and Electrical Measurements

Optical measurements on polished single-crystal slices were performed at room temperature on a Perkin-Elmer 580 single-beam scanning infrared spectrophotometer. The measurements were performed in the transmission mode over the range 2.5–25 μm . Transmission through the sample was normalized to the signal obtained in the absence of sample.

Transmission in the vicinity of the optical band edge was measured with an Oriel Model 1724 monochromator, an Oriel G 772-5400 long-pass filter, and a calibrated silicon diode detector. Optical band gaps were determined from the responses with and without the crystal in the beam.

High-temperature infrared spectra were measured in a high-temperature cell with a Nicolet Model 605X Fourier transform spectrometer having a resolution of four wave numbers.

The van der Pauw (14) method was used to measure electrical resistivities and Hall voltages from 77 to 400 K. Contacts were made by the ultrasonic soldering of indium directly onto the samples, and ohmic be-

havior was established by measuring the current-voltage characteristics. The activation energy of resistivity E_a (defined for semiconductors by $\rho = \rho_0 \exp(E_a/kT)$, where ρ = resistivity, ρ_0 is a constant, T = temperature (K), and k = the Boltzmann constant, was determined by measuring ρ as a function of T .

Results and Discussion

For ZnSiP_2 , the best crystals were obtained by chemical vapor transport. The relatively high melting point reported (2) for ZnSiP_2 precluded growing the crystals from the melt in silica tubes. However, pure ZnGeP_2 crystals were obtained by Bridgman growth from the melt and these crystals were grown crack-free when the wall of the graphite crucible was thinned sufficiently so as to allow cracking of the crucible on expansion of the product as the melt solidified.

X-ray diffraction analysis confirmed the cell parameters (see Table I) for ZnSiP_2 and ZnGeP_2 previously reported (12, 13). Microhardness measurements (Knoop indenter) were made on ZnSiP_2 and ZnGeP_2 single crystals with a Kentron microhardness tester. The results using a diamond indenter with a 100-g load gave values of 770 (100) kg/mm^2 for chemical vapor transport grown ZnSiP_2 . Crystals obtained from a zinc flux gave a much lower value. For both chemical vapor transport and melt-grown crystals of ZnGeP_2 , the Knoop hardness values were 620 (100) kg/mm^2 . The higher value for the relatively pure ZnSiP_2 sample is consistent with the tighter bonding present in the silicon chalcopyrite.

The properties for the arsenic-substituted phases $\text{ZnGeP}_{1.8}\text{As}_{0.2}$ and $\text{ZnGeP}_{1.6}\text{As}_{0.4}$ are also given in Table I. The principal effects of substitution are on the microhardness and the decrease in resistivity. The properties obtained for crystals of this composition grown by chemical vapor transport

TABLE I
 PROPERTIES OF ZnSiP₂, ZnGeP₂, ZnGeP_{1.8}As_{0.2}, AND ZnGeP_{1.6}As_{0.4}

Compound	Cell parameter		ρ (R.T.) (Ω -cm)	E_a (eV)	E_g (eV)	Hardness ^a (kg/mm ²)
	<i>a</i>	<i>c</i>				
ZnSiP ₂ (Zn Flux)	5.401(2)	10.443(2)	2.7×10^5	0.26(5)	2.00(2)	640(100)
ZnSiP ₂ (c.v.t.)	5.401(2)	10.443(2)	1.8×10^6	0.33(5)	2.00(2)	770(100)
ZnGeP ₂ (c.v.t.)	5.473(2)	10.717(2)	6.9×10^5	0.11(5) ^b 0.58(5) ^c	1.80(2)	620(100)
ZnGeP ₂ (melt)	5.469(2)	10.718(2)	3.6×10^6	0.58(5)	1.80(2)	620(100)
ZnGeP _{1.8} As _{0.2} (c.v.t.)	5.486(2)	10.753(2)				
ZnGeP _{1.8} As _{0.2} (melt)	5.480(2)	10.742(2)	2.5×10^6	0.51(5)	1.78(2)	510(100)
ZnGeP _{1.6} As _{0.4} (c.v.t.)	5.498(2)	10.775(2)				
ZnGeP _{1.6} As _{0.4} (melt)	5.492(2)	10.772(2)	1.0×10^6	0.50(5)	1.76(2)	490(100)

^a Knoop indenter at 100 g.

^b $T < 220$ K.

^c $T > 220$ K.

were essentially the same as those for melt-grown samples.

The stability of ZnSiP₂, ZnGeP₂, and ZnGeP_{1.8}As_{0.2} toward oxidation was determined by heating these compounds in a flowing oxygen stream (65 cm³/min) and by determining the change in weight during the heating period. The results are shown in Fig. 1 and indicate that ZnGeP₂ is stable up to 740°C. The ZnSiP₂ sample also begins to oxidize at approximately 740°C but the rate of its oxidation is much slower than that of ZnGeP₂. It can be noted from Fig. 1 that the substitution of 10 mole% of arsenic for phosphorus lowers the decomposition temperature considerably.

The infrared spectral response for ZnSiP₂ and ZnGeP₂ is given in Fig. 2. There are marked absorption bands for ZnSiP₂ at approximately 10 and 11.5 μ m and for ZnGeP₂ at 13 μ m. It has been reported by Isomura

and Masumoto (15) and Alekperova *et al.* (16) that these absorption bands are due to lattice vibrations. In order to demonstrate

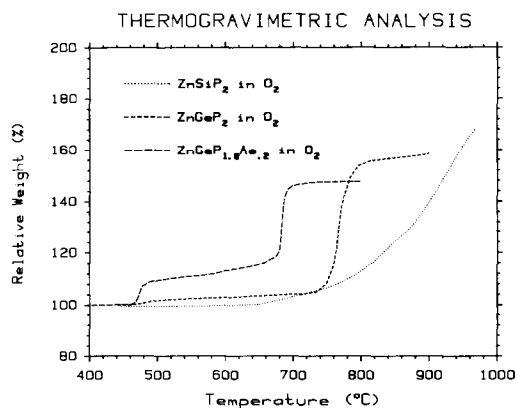


FIG. 1. Relative weight of ground crystals of ZnSiP₂, ZnGeP₂, and ZnGeP_{1.8}As_{0.2} as a function of increasing temperature in flowing oxygen.

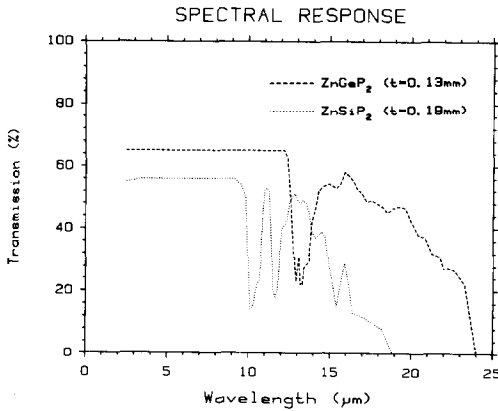


FIG. 2. Percentage of incident radiation transmitted through polished crystals of ZnGeP_2 and ZnSiP_2 .

that these bands were not caused by P–O bonds, ZnGeP_2 samples were heated in a flowing oxygen stream at 300°C for 2 hr. The spectrum of the treated samples was exactly the same as the untreated crystals. The indirect optical band gaps for ZnSiP_2 and ZnGeP_2 were obtained from plots of $(\alpha h\nu)^{1/2}$ vs energy. The values of these gaps were 2.0 and 1.8 eV, respectively. Figure 3 shows a comparison of the spectral response for pure ZnGeP_2 taken at room temperature and 400°C . It can be seen that there is very little change in the position

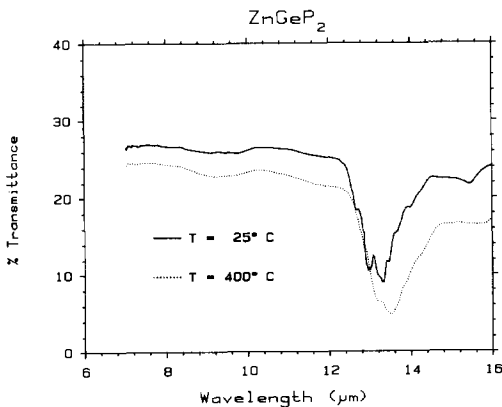


FIG. 3. Transmittance of a polished slice of ZnGeP_2 at room temperature and at 400°C .

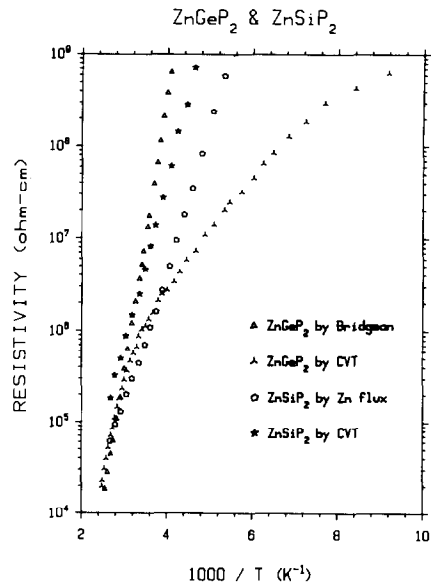


FIG. 4. Resistivity as a function of temperature for crystals of ZnGeP_2 and ZnSiP_2 grown by various techniques.

and shape of the absorption band as the temperature is increased.

A comparison of the infrared spectra of pure ZnGeP_2 and $\text{ZnGeP}_{1.8}\text{As}_{0.2}$ indicates no appreciable shift in the absorption band. In addition a weak second band appears at $9.8 \mu\text{m}$ in the transmission spectra of the 20% arsenic-substituted sample. The invariance of the principal absorption band at $13 \mu\text{m}$ for these compositions suggests that it depends primarily upon vibrations of the cations. For these reasons samples containing higher arsenic substitution were not attempted.

The activation energy of ZnSiP_2 single crystals was obtained from $\log \rho$ vs $10^3/T$ plots (Fig. 4). Within the reported experimental error, there is little difference in the results obtained from crystals grown from a zinc flux or by chemical vapor transport. For ZnGeP_2 (Fig. 4) the melt-grown crystals showed an activation energy of ~ 0.6 eV, which is consistent with the observed optical band gap of ~ 1.8 eV. The observed

activation energy for ZnSiP₂ (~0.3 eV) suggests that the material behaves as an extrinsic semiconductor. The substitution of arsenic for phosphorus in ZnGeP₂ did not significantly affect the variation of resistance with temperature. In addition, the high values of the resistivity prevented measurement of the Hall effect.

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